## GrapheneforUS

## Karolina Piętak ${ }^{1,2}$

Jakub Jagiełło ${ }^{1}$, Artur Doborowolski¹, Tymoteusz Ciuk ${ }^{1}$
${ }^{1}$ Łukasiewicz Research Network - Institute of Microelectronics and Photonics, Al. Lotników 32/46, 02-668
Warsaw, Poland
${ }^{2}$ Faculty of Chemistry, Warsaw University of Technology, ul. Noakowskiego 3, 00-664 Warsaw, Poland

## Enhancement of graphene-related and substrate-related Raman modes through dielectric layer deposition

In this work, we demonstrate a method for the enhancement of Raman active modes of hydrogen-intercalated [1] quasi-free-standing epitaxial chemical vapor deposition graphene and the underlying semi-insulating $6 \mathrm{H}-\mathrm{SiC}(0001)$ substrate through constructive signal interference within atomic-layer-deposited amorphous $\mathrm{Al}_{2} \mathrm{O}_{3}$ passivation. We find that an optimum $\mathrm{Al}_{2} \mathrm{O}_{3}$ thickness of 85 nm for the graphene 2 D mode and one of 82 nm for the SiC longitudinal optical $\mathrm{A}_{1}$ mode at $964 \mathrm{~cm}^{-1}$ enable a $60 \%$ increase in their spectra intensities. We demonstrate the method's efficiency in Raman-based determination of the dielectric thickness and highresolution topographic imaging of a graphene surface $[2,3]$.

## References

[1] M. Szary, S. El-Ahmar, T. Ciuk, Applied Surface Science, 541 (2020) 148668.
[2] K. Piętak, J. Jagiełł, A. Dobrowolski, R. Budzich, A. Wysmołek, T. Ciuk, Applied Physics Letters, 120 (2022) 063105.
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Figures


Figure 1: Schematic of the two considered systems. Theoretical and experimental enhancement factor (EF) for the SiC LO $\mathrm{A}_{1}$ mode, the Si mode and the QFS graphene 2D mode all as a function of the $\mathrm{Al}_{2} \mathrm{O}_{3}$ physical thickness. High-resolution Raman map of hydrogen-intercalated QFS epitaxial CVD graphene on semiinsulating vanadium-compensated on-axis 6 H $\mathrm{SiC}(0001)$ passivated with 69 -nm-thick $\mathrm{Al}_{2} \mathrm{O}_{3}$ : (a) Graphene 2D mode FWHM . (b) Relative intensity of the SiC longitudinal optical $\mathrm{A}_{1}$ mode at $964 \mathrm{~cm}^{-1}[2]$.

